

Title (en)

Device for moving a substrate holder during a vertical gal-vanic metal deposition, and a method for vertical galvanic metal deposition using such a device

Title (de)

Vorrichtung zum Bewegen eines Substrathalters während einer vertikalen galvanischen Metallabscheidung und Verfahren zur vertikalen galvanischen Metallabscheidung unter Verwendung solch einer Vorrichtung

Title (fr)

Dispositif pour déplacer un support de substrat pendant un dépôt de métal galvanique vertical et procédé de dépôt de métal galvanique vertical utilisant un tel dispositif

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Application

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Priority

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Abstract (en)

The present invention is related to device for moving a substrate holder, which comprises at least a substrate to be treated, during a vertical galvanic metal, preferably copper, deposition on such a substrate to be treated characterized in that the device comprises at least a first driving means, at least a second driving means, at least a first adjusting means and at least a second adjusting means; wherein the first driving means is in operative connection to the first adjusting means to generate a first axial deflection and the second driving means is in operative connection to the second adjusting means to generate a second axial deflection of the substrate holder; wherein said first axial deflection and said second axial deflection are continuously adjustable and/or controllable. The invention is further related to a method for vertical galvanic metal, preferably copper, deposition on a substrate using such a device.

IPC 8 full level

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CPC (source: EP)

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Citation (search report)

- [X] DE 4212045 C1 19931202 - SCHERING AG [DE]
- [X] DE 102005024771 A1 20061123 - HANSGROHE AG [DE]
- [X] US 2002071917 A1 20020613 - HEPTING EMIL [DE]
- [X] US 2004037682 A1 20040226 - YOSHIOKA JUNICHIRO [JP], et al
- [X] GB 2247027 A 19920219 - HENIG HANS
- [X] EP 1441048 A2 20040728 - DAINIPPON SCREEN MFG [JP]

Cited by

EP3176288A1; CN108138347A; US10407788B2; WO2017093382A1

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